



XK20 alignment laser















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XK20 hardware











Principles of measurement

XK20 is an alignment laser kit capable of performing various tasks including but not limited to:

- Machine tool alignment to recognised standards during manufacture
- Set-up of manufacturing lines
- Service activity, such as machine realignment
- Pre-machining alignment

Measurement capability includes:

Translational modes

- Straightness
- Long range straightness
- Squareness
- Parallelism



System components

1	Launch unit A laser transmitter with a 360 degree sweeping head and pentaprism optic.
2	S unit The 'Stationary' unit, containing a position sensitive detector (PSD).
3	M unit The 'Motion' unit, containing a position sensitive detector (PSD).
4	Display unit A touch screen tablet containing the measurement software and user guide.
5	Low profile magnetic base A magnetic base used for mounting the S unit, M unit, pentaprism or Launch unit in conjunction with other brackets and accessories.
6	Tripod translation stage The XK20 tripod translation stage allows for precise translation of the Launch unit. A fail-safe, quick release mechanism allows mounting to a tripod.
7	Launch L-bracket Upright bracket that enables the user to mount the Launch unit at a 90 degree angle.
8	M6 pillars × 4 150 mm pillars that can be screwed into magnetic bases for mounting the S unit, M unit and pentaprism.
9	M6 short pillars × 4 70 mm pillars that can be screwed into magnetic bases for mounting the S unit, M unit and pentaprism.
10	Universal power supply kit (not pictured) This includes; 1 × power supply and 3 × kettle leads for UK, EU and USA sockets.
11	DC split cable (not pictured) This cable allows for the charging of three system devices from a single power source (Launch unit, M unit and S unit).

NOTE: To see the parts used in different set-up assemblies, refer to the XK20 hardware guide.







System components continued

1	Pentaprism optic The pentaprism optic can be used to reflect the beam 90 degrees for horizontal parallelism measurements and some squareness measurements.
2	Launch spindle mount The Launch spindle mount is used to mount the Launch unit into a spindle or chuck for rotational measurements.
3	Transceiver spindle bracket The transceiver spindle bracket is used to mount either the M unit or the S unit in a spindle or chuck for rotational measurements
4	90 degree transceiver bracket The 90 degree transceiver bracket can be screwed onto either the M unit or the S unit to allow 90 degree mounting when used with the magnetic bases, mounting posts or spindle brackets.
	Transceiver lowering bracket The transciever lowering bracket enables the lowering of the M unit when fixtured to the rotary magnetic base.
6	Pentaprism translation stage The pentraprism translation stage is for use with the pentaprism optic to allow lateral adjustment during measurements. The stage is mounted to a low profile magnetic base.
	Rotary magbase The XK20 magnetic base has a rotating head so that the M unit can be rotated when taking flatness measurements. The base has an on/off switch. It is used for mounting the M unit or S unit in combination with the M6 pillars.
	Tripod The tripod provides a stable mounting for the Launch unit and allows the height to be adjusted.
	Magnetic reference mount The XK20 magnetic reference mount enables the M unit to be magnetically mounted against the reference edge of a casting. The M unit can be mounted in a fixed position or on to the rotary head of the magnetic reference mount.
10	USB-DC adapter The display unit can be used to charge the M unit and S unit during use with the USB-DC adapter.



XK20 Applications





Launch unit

The launch unit contains a fibre-coupled diode laser, which produces a stable Class 2 output laser beam.

The output beam can be flipped between two orientations using the pentaprism optic in the sweeping head.

WARNING: Do not conduct a measurement whilst the launch unit is charging.

The launch unit contains a rechargeable lithium-ion battery and is charged using the power supply or via the XK20 display unit, in conjunction with the DC-USB adaptor and split cable. It is recommended that the launch unit should be charged before or after every use to maintain the battery.

Specifications about the power supply can be found on page 13.

1	Power on/off, change display view
2	Display
3	Laser head
4	Fine head adjustment dial
5	Pitch/yaw screw
6	Release lever
7	Charging port
8	Launch pentaprism





M unit and S unit

The M unit is a wireless device used as the main detector in all measurements.

The S unit is a wireless device primarily used in rotational alignment applications.

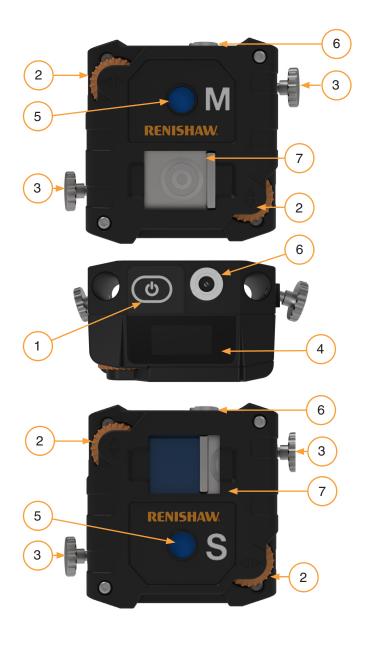
The detection of position is provided by a 2-axis position sensitive diode (PSD). The unit features a Class 2 laser diode output which allows the device to be used with the M unit.

WARNING: Do not conduct a measurement whilst the M unit and S unit are charging.

The M unit and S unit both contain a rechargeable lithium-ion battery. The M unit and S unit are charged using the power supply or via the XK20 display unit, in conjunction with the DC-USB adaptor and split cable. It is recommended that the M unit and S unit should be charged before or after every use to maintain the battery.

Specifications about the power supply can be found on page 13.

1	Power on/off
2	Pitch/yaw adjuster
3	Clamp screw
4	Device status display
5	Laser output
6	Charging connector ports
7	PSD receiver / target shutter







Display unit

The display unit is used for hardware set up and data capture.

WARNING: Do not conduct a measurement whilst the display unit is charging.

The display unit contains a rechargeable lithium-ion battery and is charged using the power supply. It is recommended that the display unit should be charged before or after every use to maintain the battery.

Specifications about the power supply can be found on page 13.

1	Battery status button
2	Power on/off
3	'Capture' button
4	Touch screen
5	Battery status LED's
6	HDMI port
7	USB A port
8	USB C port
9	Charging port









System specifications

XK20 system	
Specified accuracy range	−10 °C to 50 °C
Recommended recalibration period	2 years

Launch unit	
Beam measurement range	40 m
Laser output	Class 2
Dimensions	147 mm × 136 mm × 152 mm
Weight	2.26 kg
Power	2 × Lithium-ion (7.4 Wh) internal batteries
Operating time	~30 hours
Warm-up time	Valid when the unit has been stored in room temperature and measurement takes place in the same environment.
Digital spirit level accuracy	20 μm/m +/-1%
Digital spirit level resolution	0.001mm/m
IP rating	N/A

M unit and S unit		
Beam measurement range	20 m	
Laser output	Class 2	
Dimensions	76 mm × 76.4 mm × 45.9 mm	
Weight	272 g	
Power	Lithium-ion (7.4 Wh) internal battery	
Operating time	~24 hours	
Warm-up time	~30 minutes	
Inclinometer accuracy	±1°	
Inclinometer resolution	0.1°	
IP rating	IP 66/67 (IEC 60529)	





Display unit	
Dimensions	269 mm × 190 mm × 49.4 mm
Weight	1.4 kg
Power	Lithium-ion (68.04 Wh) internal battery
Operating time	~16 hours (internal battery only)
Screen size	8 in
Wireless range	30 m
IP rating	IP 66/67 (IEC 60529)

System storage and transportation environment

Storage and transportation	
Temperature	−20 °C to +50 °C
Pressure	1000 mb – 700 mbar
Humidity	10 % to 95% RH (non-condensing)

XK20 Hardware

XK20 Software

XK20 Applications





Translational measurements - performance specifications



Straightness	
Range	±5 mm
Accuracy	±0.008A ±0.8 μm
Resolution	0.1 μm

A = displayed straightness reading (μm)



Squareness	
Range	±5 mm
Accuracy*	±0.008A/M ±1.4/M ±4 μm/m
Resolution	0.1 μm

^{*} with squareness calibration factor

 $A = straightness reading of the furthest point (<math>\mu m$)

M = length of the (shortest) axis (m)



Parallelism	
Range	±5 mm
Accuracy (i)	±0.008A/M ±1.4/M ±2 μm/m*
Accuracy (ii)	±0.008A ±1.4 ±2M μm*
Resolution	0.1 μm

^{*} laser to pentaprism distance > 0.2 m

A = (largest) straightness reading (μm)

M = length of the axis (m)

- i. To be used when the quantity of interest is the angle between rails.
- ii. To be used when parallelism between rails is:
- specified as a tolerance zone defined by two parallel lines parallel to a datum axis (for example, reference rail) within where the axis of the feature (for example, measurement rail) must lie.
- intended as a point by point variation in the separation between the rails, with respect to the separation between the first two points





Power supply

Power supply	
Input voltage	100 V to 240 V
Input frequency	63Hz
Maximum input current	2.0 A
Output voltage	15 V
Maximum output current	4 A
Safety standard	EN 62368

NOTE: The power supply has been qualified for use with the XK20 system. Do not use an alternative power supply. If the power supply becomes damaged or lost, a new supply can be purchased from **Renishaw's online store** or contact your **local Renishaw office**.

Weights and dimensions

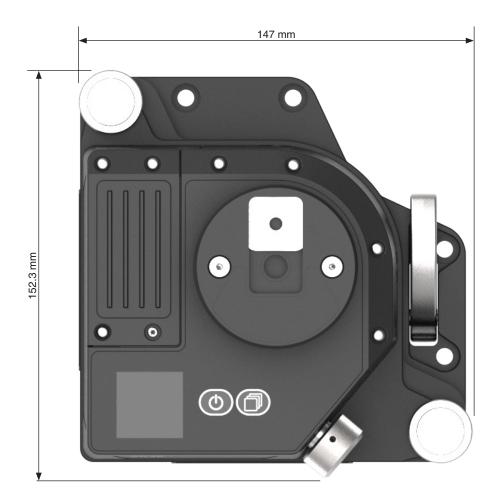
Item	Weight (approximately)
XK20 system	Maximum 25 kg
Launch unit	2.26 kg
Display unit	1.4 kg
M unit	272 g
S unit	272 g

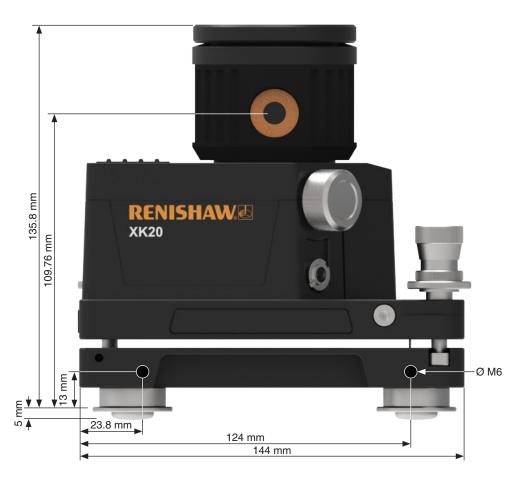




Launch unit

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XK20 Hardware

XK20 Software

XK20 Applications





Display unit



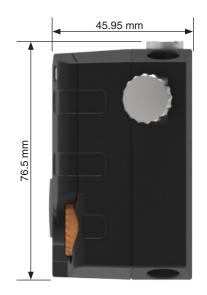




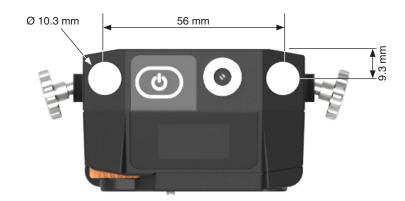


M unit

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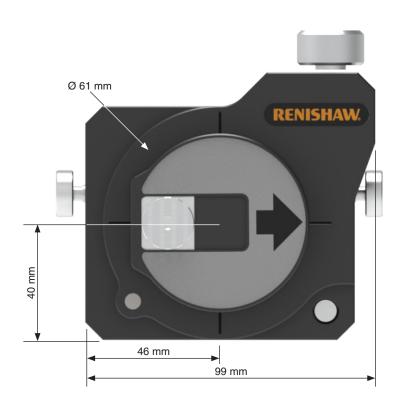


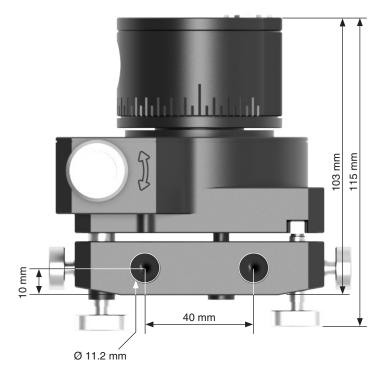






Pentaprism optic



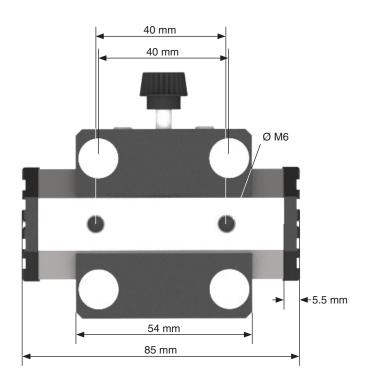


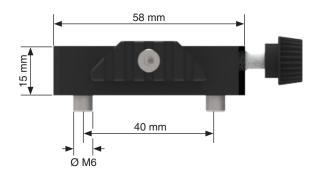
18





Pentaprism translation stage





XK20 software





Display unit and software overview

Abbreviations

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The software uses a range of abbreviations. Whilst they may be clear in context, the table below shows their long form:

Abbreviation	Long form
Std. Dev.	Standard deviation
Pos	Position
Н	Horizontal
V	Vertical
Ref	Reference
Sec	Secondary
M-H	M unit – horizontal
M-V	M unit – vertical
H Ref	Horizontal reference
V Ref	Vertical reference
H Sec	Horizontal secondary
V Sec	Vertical secondary
H Par	Horizontal parallel straightness
V Par	Vertical parallel straightness
Max	Maximum
Min	Minmum



NOTE: If using the XK20 display unit, software updates can be found on the Renishaw website (**www.renishaw.com/calsoftware**). See **Appendix D** for further information on updating the display unit.

If using a third party tablet, software can be installed and updates will be available from the relevant application store. Search for the 'Renishaw CARTO XK20 App'.

XK20 applications







Introduction

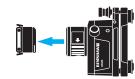
Translational measurement modes

This guide includes:



Straightness

Measures vertical and horizontal straightness along an axis. Used for all machine builds to ensure accuracy when mounting and aligning stages and guideways.

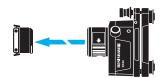


This is done by measuring the position of the launch beam when moving the M unit along the axis under test.



Long range straightness

Measures vertical and horizontal straightness along an axis. Used for all machine builds to ensure accuracy when mounting and aligning stages and guideways.

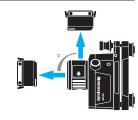


This is done by measuring the position of the launch beam when moving the M unit along the axis under test.



Squareness

Measures the orthogonality of two machine axes. This would typically be used to ensure that machine arms and beds are at right angles, to align machine rails, or when squaring separate machine assemblies.



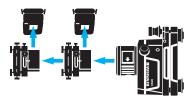
This consists of two straightness measurements done at 90 degrees to one another.



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Parallelism

Measures the straightness deviation or overall misalignment angle between two nominally parallel axes. It is typically used during the manufacture of machine tool structures.



This is done by using the optional pentaprism optic to direct the beam along the axes, taking measurements with the M unit while keeping the launch unit as a fixed reference.





Measurement considerations

Alignment

Alignment is the process of making the laser beam parallel to the axis being measured. This forms a datum from which the straightness deviation along the axis can be measured. Optimal alignment reduces slope error and PSD scale error.

Slope error

Slope error is caused by poor alignment. This can be reduced by the following steps:

- 1. Minimise misalignment of the beam to the axis to reduce PSD scale error by ensuring the software target stays green along the entire rail.
- 2. End-point fit data to remove residual slope error.

PSD scale error

Large misalignments along the axis increases PSD scale error which is inherent in PSD technology. Aligning the beam within the advised alignment tolerance will minimise this error. Ensuring the beam is aligned as close to the PSD centre as possible will also minimise this error.

Coning

Coning is the process of making the laser beam parallel to the axis of the spindle being measured. This forms a datum from which the spindle direction error can be measured.

Environment

The environmental conditions during measurements will significantly affect measurement accuracy. The factors listed can introduce noise and drift to measurements. These should be reduced or eliminated where possible before commencing.

- Thermal stability
- Shock and vibration
- Air turbulence

Once minimised, any further noise can be reduced using **detector value** filter (see Appendix E for details).

Alignment tolerances

To minimise slope error and the effects of PSD scale error, aim to align the laser beam to within the following tolerances:

Software tolerance

Ensure the software target stays green along the axis being measured. For numerical values, tap the software target on the screen.

Geometric tolerance

±100 µm* along the axis being measured.

This is confirmed by the alignment target turning green.

Rotational tolerance

Coning alignment should be $\pm 100~\mu\text{m}^*$ through a 180 degree rotation.

* Environmental conditions permitting



ISO standards

The International Organisation for Standardisation (ISO) publishes a set of internationally recognised guidelines that ensure a consistent quality of performance. XK20 is compliant to ISO 230 which specifies the use of alignment lasers to measure a range of machine tool geometric features.

Furthermore, XK20 can provide data analysis against the following standards for machine tool building:

- ISO 10791
- ISO 3070

It's important to understand that each ISO standard is specific to a certain kind of machine type. For example ISO 10791:1:2015 is only referenceable against machine tools with Horizontal spindles as their Z axis.

The table below offers further detail:

Standard	Title	Subtitle	Description	Notes
ISO 230-11:2018	Test code for machine tools.	Measuring instruments suitable for machine tool geometry.	This standard documents the characteristics of precision measuring instruments for testing the geometric accuracy of machine tools.	
ISO 10791-1:2015	Test conditions for machining centres.	Part 1: Geometric tests for machines with horizontal spindle (horizontal Z axis).	This standard specifies the geometric tests and tolerances for machining centres with horizontal spindles.	Methods based on measurements of angles (auto-collimators) (ISO 230-1:2012, 12.1.3) shall not be applied as these methods are restricted to measurements of functional surfaces.
BS ISO 10791-2:2023	Test conditions for machining centres.	Geometric tests for machines with vertical spindle (vertical Z-axis).	This standard specifies the geometric tests and tolerances for machining centres with vertical spindles.	Methods based on measurements of angles (auto-collimators) (ISO 230-1:2012, 12.1.3) shall not be applied as these methods are restricted to measurements of functional surfaces.
BS ISO 3070-1:2007	Test conditions for testing the accuracy of boring and milling machines with horizontal spindles.	Machines with fixed column and moveable table.	This standard specifies geometric tests and tolerances for horizontal spindle boring and milling machines that have a fixed column and movable table.	
BS ISO 3070-2:2016	Test conditions for testing the accuracy of boring and milling machines with horizontal spindles.	Machines with moveable column along the X-axis.	This standard specifies geometric tests and tolerances for horizontal spindle boring and milling machines that have a moveable column along the X-axis.	
BS ISO 3070-3:2007	Test conditions for testing the accuracy of boring and milling machines with horizontal spindles.	Machines with moveable column and moveable table.	This standard specifies geometric tests and tolerances for horizontal spindle boring and milling machines that have a moveable column & table.	



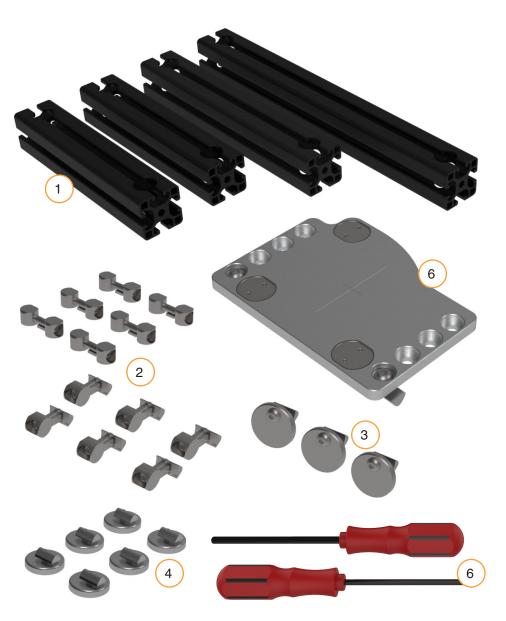


Appendix A

XK20 fixturing kit

1	Extrusions Aluminium box section extrusions (350 mm, 250 mm and 2×200 mm) that can be connected together in numerous variations using the supplied connectors.
2	Extrusion connectors × 12 6 off universal fastenings and 6 off universal butt fastenings that can be used to connect extrusions.
3	Magnets × 6 These magnets are used to fix the extrusion securely to a machine bed or casting.
4	Position discs x 3 These discs are used to position the extrusion on the machine bed and prevent lateral movement.
5	Hex drivers (4 mm, 5 mm) Allen keys to fasten extrusion connectors, position discs and magnets.
6	Launch unit extrusion mount The mount allows the launch unit to be attached to an extrusion for more versatile mounting. The launch unit can be fixed to the plate using the built in magnetic feet. The plate is lined with 8 through holes for mounting to an extrusion with the provided connectors.

NOTE: To see the parts used in different set-up assemblies, refer to the XK20 Hardware Guide.







Appendix B

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Renishaw 2012 analysis explained

Statistics are calculated once measurements have been completed and displayed as shown here.

Statistic	٧	Н
Peak-Peak (mm)	0.035	0.016
Standard Deviation (mm)	0.013	0.008
Max (mm)	0.007	0.011
Min (mm)	-0.028	-0.012

Magnitude of deviations

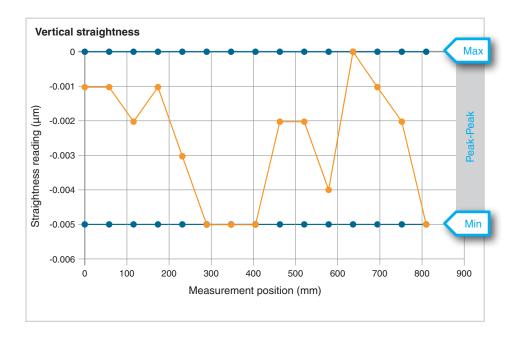
Max and Min

Max and Min are the maximum and minimum straightness deviations along the measured axes.

Peak-peak

This is the difference between the maximum and minimum straightness values.

These are useful statistics for determining whether an alignment is within assembly tolerances and understanding the size of deviation along an axis.



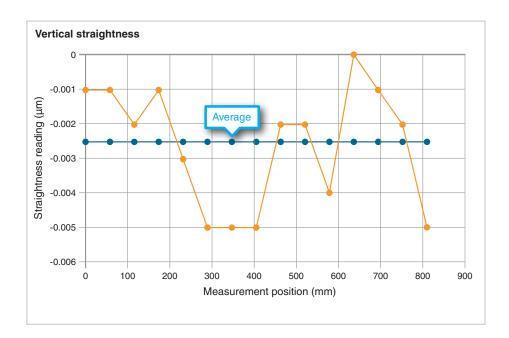


Renishaw 2012 analysis explained

Deviation from the average

Standard deviation (STD)

Standard deviation (STD) represents the amount of deviation/spread from the average. It represents the uniformity of straightness, i.e. the smaller the STD, the better the straightness. Therefore, an axis with a very small STD would be considered very 'straight'.







Appendix C

ISO standard analysis explained

Max / min local deviation

This is the deviation that occurs along a length defined by the specific standard that is selected. For example for ISO 10791-2 the defined local length is 300 mm. The max / min deviation that is allowed in order to comply with 10791-2 is \pm 0.007 mm. This will be highlighted in red if outside of specification.

Global deviation

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This is the deviation that occurs across the entire measurement length. Each standard specifies a tolerance for a given measurement length, refer to the relevant ISO standard to find the tolerance that relates to your measurement length for global deviation compliance.

ISO 10791-2 (0.	007mm/300	mm) v
Deviation	V (mm)	Section (mm)
Global	0.016	0-2000
Max local	0.013	800-1100
Min local	0.003	1600-1900
Deviation	H (mm)	Section (mm)
Global	0.037	0-2000
Max local	0.037	600-1100
Min local	0.002	1600-1900



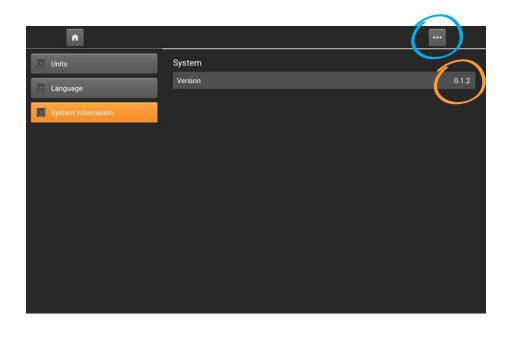


Appendix D

Updating the XK20 display unit software

The display unit software must be updated manually via USB*. It is recommended to check the Renishaw website periodcially for software updates. Your local Renishaw office may also send out communications.

- Download the software from the Renishaw website (www.renishaw.com/calsoftware) and transfer it on to an empty USB stick.
- 2. Ensure the display unit is turned off. Plug in the USB stick.
- 3. Power on the display unit. The display unit will load to the home screen.
- 4. Power off the display unit. Once powered off, remove the USB stick.
- Power on the display unit. Check the version number has updated in settings.



^{*}Renishaw does not provide a USB.

Median Averaging



Appendix E

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Filtering vs averaging

XK20 uses a median filter instead of averaging. The reason for this is that median filters are better suited to smooth sudden fluctuations caused by air turbulence and random vibrations.

With averaging, when data is captured (for example, 4 second averaging) the average of all data points over a 4 second period is returned; this means that noisy data is also included in the result. However, with a median filter, noisy data points are replaced with the median data point within the sample.

Paw Data — Median Filter

Raw Data — Median Filter

Raw Data — Median Filter

10

8

6

4

2

-2

-4

-6

0

5

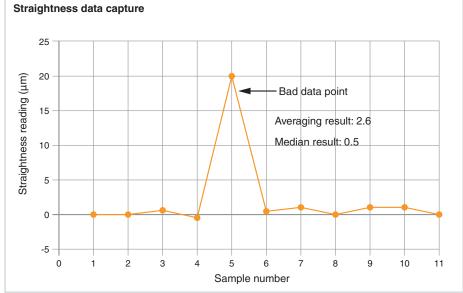
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15

20

25

Time



NOTE: Median filtering is part of the reason you may get different straightness results when compared to laser interferometers.



Filtering

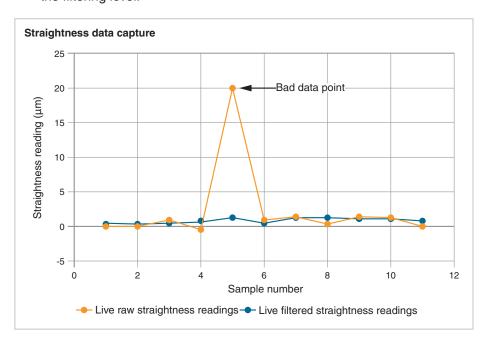
XK20 uses median filters in two ways:

1. Live median filter

The live filter smooths the raw readings from the M unit and S unit and replaces each data point with the median of the corresponding set of data points. The size of this set of data points is dependent on the filtering level.

2. Median filter at data capture

When data is captured, a sample of data is taken, and the system returns the median value of the sample. The size of the sample is dependent on the filtering level.



Live raw straightness readings	Live filtered straightness readings	Me
0	= median (0, 0, 0.5) = 0	filt
0	= median (0, 0.5, -0.5) = 0	ca
0.5	= median (0.5, -0.5, 20) = 0.5	
-0.5	0.5	
20	1	
0.5	0.5	
1	1	
0	1	
1	1	
1	1	
0	0.5	

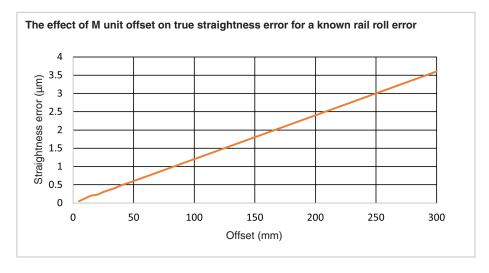


Appendix F

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Parallelism – combined horizontal and vertical

When measuring combined parallelism between two rails, the true straightness error can be affected by the roll of the carriage along the axis of travel. This roll error of the carriage combined with the M unit being offset from the carriage can cause the measured straightness error to appear larger than the true straightness error. This is why it is important to minimise the offset of the M unit from the point of interest.



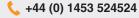
This is based on an example rail and carriage to have a known roll error of 20Arc seconds.



apply innovation™

www.renishaw.com/xk20







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